

Morphological characterization of N-doped TiO₂ thin films

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Abstract— Metallorganic chemical vapor deposition was used to grown TiO₂ and N-doped TiO₂ on borosilicate substrates at 400°C. Titanium isopropoxide IV was used as titanium and oxygen precursors and ammonia as nitrogen source. Analyses by atomic force microscopy showed that both films presented rounded well-defined grains. The results showed that nitrogen doping resulted in a decrease in the mean grain size and in the surface roughness.

Keywords— *TiO₂, thin films, N-doped TiO₂.*

I. INTRODUCTION

Titanium dioxide is a semiconductor that can be produced in the form of powders and films. It is friendly to the environment and exhibits good chemical stability, corrosion resistance, photostability and band gap energy compatible with sunlight¹⁻². TiO₂ presents allotropy in three crystalline phases: anatase, rutile and brookite. The rutile phase is the most stable thermodynamically, and anatase presents higher photocatalytic efficiency³. Due to its physical and chemical properties, TiO₂ has been used in many applications, from automotive sector to human health. In recent decades, it has been used as a photocatalyst in the photodegradation of organic pollutants and bacteria^{2,4,5}. However, the high band gap values of 3.2 eV for anatase and 3.0 eV for rutile⁶ limits its use as a photoactive material since it is activated only by UV light, which corresponds to about 3-4% of the solar spectrum⁷. Thus, an alternative that has been explored to allow its use under visible light is the doping of TiO₂ with metals or non-metals^{6,8}. According to Reddy et al.⁹, the doping with anions such as N, S and C alters the conductivity and the optical properties by introducing new surface states near the conduction or the valence band of the TiO₂. Asahi et al.¹⁰ proposed that, in anatase nitrogen-doped TiO₂ the oxygen atoms are replaced by nitrogen atoms. The small difference between the ionic radii would facilitate this substitution and would not cause great distortion of the crystalline lattice. In this context, considering that the morphology, the roughness and the grain size influence the photocatalytic efficiency of TiO₂ films¹¹, the goal of this study was to grow films of TiO₂ and N-doped TiO₂ for use in photocatalysis, and to characterize the surface properties.

II. MATERIAL AND METHODS

Borosilicate substrates were cleaned in a 5% H₂SO₄ aqueous solution, rinsed in deionized water in abundance, dried in nitrogen and immediately inserted into the reactor chamber. Thin films of TiO₂ and N-doped TiO₂ were grown by metallorganic chemical vapor deposition (MOCVD) at 400° C for 40 minutes under a pressure of 50 mbar. Fig.1 shows schematically the MOCVD equipment. For the growth of TiO₂ films titanium isopropoxide IV was used as precursor of both titanium and oxygen. Nitrogen was used as vector and purge gas. To produce the N-doped TiO₂ films, ammonia was introduced into the system during the growth. The nitrogen and ammonia flows were set in 0.5 mL/min. The morphology, roughness and mean grain size were evaluated by atomic force microscopy (AFM) on a Bruker SPM equipment, model NanoScope IIIA.

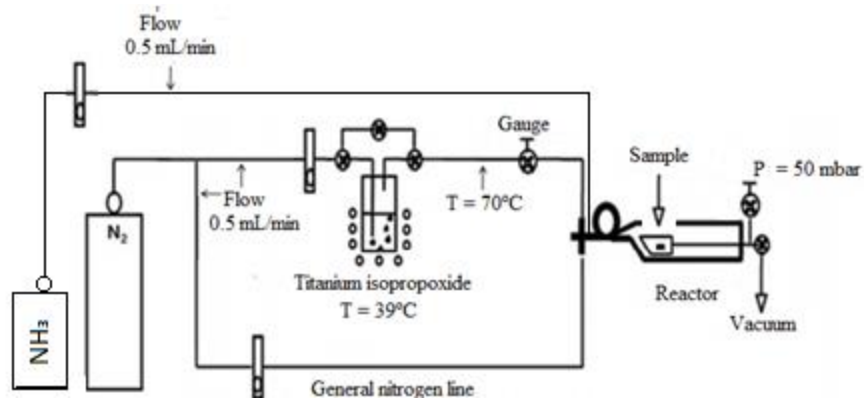


Figure 1: MOCVD equipment shown schematically (adapted from reference 12)

III. RESULTS AND DISCUSSION

Fig.2 and 3 show the AFM topography of TiO_2 and N-doped TiO_2 thin films. Rounded and well defined grains can be observed in these surfaces. From Tab.1 it can be seen that the undoped film presented mean grain size of 96 nm and roughness of 19 nm, and the N-doped TiO_2 film presented 67 nm and 4 nm for mean grain size and roughness, respectively. According to our results it was found that the surface roughness and the mean grain size decrease in N-doped TiO_2 films.

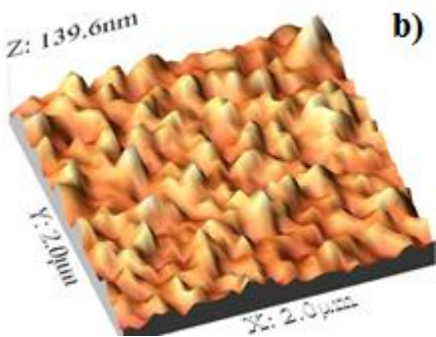
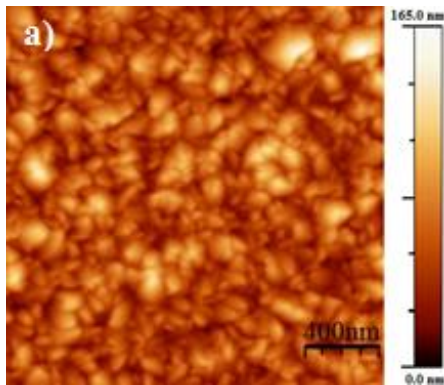


Fig.2 AFM image of the TiO_2 film grown at 400°C (a) topography; (b) 3D image.

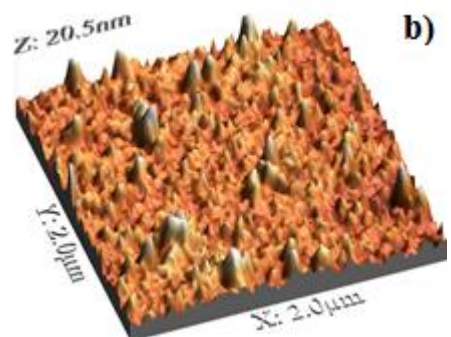
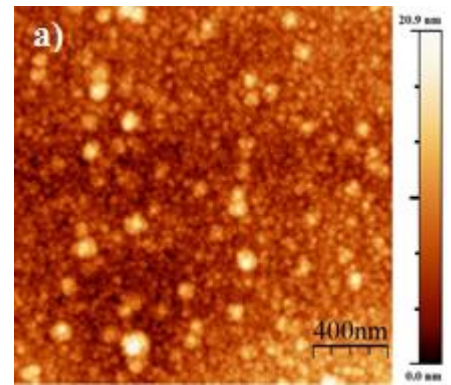


Fig.3 AFM image of the N-doped TiO_2 film grown at 400°C (a) topography; (b) 3D image

TABLE 1 - MEAN GRAIN SIZE AND RMS (ROOT MEAN SQUARE) ROUGHNESS FOR N-DOPED AND UNDOPED TiO₂ THIN FILMS

	Mean Grain Size	RMS roughness
undoped TiO ₂	96 nm	19 nm
N-doped TiO ₂	67 nm	4 nm

IV. CONCLUSIONS

The MOCVD process allows to grow undoped and N-doped TiO₂ films. Nitrogen doping decreased the grain size and the surface roughness of TiO₂ films. In fact, the TiO₂ film presented a mean grain size of 96 nm and roughness of 19 nm, whereas the N-doped TiO₂ film showed a mean grain size of 67 nm and roughness of 4 nm.

V. REFERENCES

- [1] S.A. Khayyat, R. Selvin, L.S. Roselin, A.J. Umar. "Photocatalytic Oxidation of Phenolic Pollutants and Hydrophobic Organic Compounds in Industrial Wastewater Using Modified Nonosize Titanium Silicate-1 Thin Film Technology", *Nano. Nanotech*, 14, (2014) 7345-7350.
- [2] O. Carp, C.L. Huisman, A. Reller. "Photoinduced reactivity of titanium dioxide", *Progress in Solid State Chemistry*, 32, (2004) 33-177.
- [3] K. Thamaphat, P. Limsuwan, B. Ngotawornchai. "Phase characterizaton of TiO₂ powder by XRD and TEM", *Nat. Sci*, 42, (2008) 357-361.
- [4] D. Jun, et al. "Photocatalytic Activity, Antibacterial Effect, and Photoinduced Hydrophilicity of TiO₂ Films Coated on a Stainless Steel Substrate", *Journal of Rare Earths*, 33:2, (2015) 148-153.
- [5] C. Kim, M. Choi, J. Jang. "Nitrogen-doped SiO₂/TiO₂ core/shell nanoparticles as highly efficient visible light photocatalyst", *Catalysis Communications*, 11, (2010) 378-382.
- [6] M. Dhayal, R. Kapoor, P.G. Sistla, R.R. Pandey, S. Kar, K.K. Saini, G. Pande. "Strategies to prepare TiO₂ thin films, doped with transition metal ions, that exhibit specific physicochemical properties to support osteoblast cell adhesion and proliferation", *Materials Science and Engineering*, 37, (2014) 99-107.
- [7] F.D. Duminica, F. Maury, F. Senocq. Atmospheric pressure MOCVD of TiO₂ thin films using various reactive gas mixtures. *Surface & Coatings Technology*, 188-189, (2004) 255-259.
- [8] J. Reszczynska et al. "Photocatalytic activity and luminescence properties of RE³⁺-TiO₂ nanocrystals prepared by sol-gel and hydrothermal methods", *A. Applied Catalysis B: Environmental*, 181, (2016) 825-837.
- [9] K.M. Reddy et al. "S-, N-and C-doped titanium dioxide nanoparticles: synthesis, characterization and redox charge transfer study", *Journal of Solid State Chemistry*, 178, (2005) 3352-3358.
- [10] R. Asahi et al. "Visible-light photocatalysis in nitrogen-doped titanium oxides", *Science*, 293, (2001) 269-271.
- [11] Y. Ao, J. Xu, D. Fu, C. Yuan. "Preparation of porous titania thin film and its photocatalytic activity", *Applied Surface Science*, 255, (2008) 3137-3140.
- [12] B.A. Marcello, G.A. Geribola, M.F. Pillis. "Caracterização de filmes finos de TiO₂ crescidos sobre borossilicato". In: *Anais do XXI Congresso Brasileiro de Engenharia e Ciência dos Materiais*. Cuiabá: XXI CBECIMAT, 1, (2014) 768-775.